

## Memristive devices for computing

J. Joshua Yang, Dmitri B. Strukov and Duncan R. Stewart

**Table S1 Various insulator materials use in anion devices (VCM). Top electrode (TE), bottom electrode (BE), switching modes and references are also listed for each.**

Insulators	Bottom Electrode	Top electrode	Switching mode	reference
MgO	Pt	Pt	Unipolar	1
TiO <sub>x</sub>	Ru, Pt	Al, Pt	Non/Uni/Bipolar	2, 3
ZrO <sub>x</sub>	P <sup>+</sup> -Si , n <sup>+</sup> -Si	Pt, Cr	Uni/Bipolar	4-6
HfO <sub>x</sub>	TiN	TiN	Bipolar	7
VO <sub>x</sub>	N/A	N/A	Threshold	8, 9
NbO <sub>x</sub>	P <sup>+</sup> -Si	Pt	Unipolar	10
TaO <sub>x</sub>	Pt, Ta	Pt, Ta	Bipolar	11, 12
CrO <sub>x</sub>	TiN	Pt	Bipolar	13
MoO <sub>x</sub>	Pt	Pt-Ir	Uni/Bipolar	14
WO <sub>x</sub>	W, FTO	TiN, Au	Bipolar	15, 16
MnO <sub>x</sub>	Pt	Al, TiN	Bipolar	17, 18
FeO <sub>x</sub>	Pt	Pt	Non/Bipolar	19, 20
CoO <sub>x</sub>	Pt	Pt	Nonpolar	21
NiO <sub>x</sub>	Pt	Pt	Nonpolar/Threshold	22, 23
CuO <sub>x</sub>	TiN, TaN, SRO, Pt	Pt	Bipolar	24
ZnO <sub>x</sub>	Pt, Au	TiN, Ag	Bipolar	25-27
AlO <sub>x</sub>	Ru, Pt	Pt, Ti	Unipolar/Bipolar	28, 29
GaO <sub>x</sub>	ITO	Pt, Ti	Bipolar	30
SiO <sub>x</sub>	Poly-Si, TiW	Poly-Si, TiW	Unipolar	31
SiO <sub>x</sub> N <sub>y</sub>	W	Cu	Bipolar	32
GeO <sub>x</sub>	ITO, TaN	Pt, Ni	Bipolar	33, 34
SnO <sub>2</sub>	Pt	Pt	Unipolar	35
BiO <sub>x</sub>	Bi	W, Re, Ag, Cu	Bipolar	36
SbO <sub>x</sub>	Pt	Sb	Unipolar/Bipolar	37
SmO <sub>x</sub>	TiN	Pt	Bipolar	38
GdO <sub>x</sub>	Pt	Pt	Unipolar	39
YO <sub>x</sub>	Al	Al	Unipolar	40
CeO <sub>x</sub>	Pt	Al	Bipolar	41
EuO <sub>x</sub>	TaN	Ru	Uni/Bipolar	42, 43
PrO <sub>x</sub>	TaN	Ru	Bipolar	42, 43
ErO <sub>x</sub>	TaN	Ru	Unipolar	42, 43
DyO <sub>x</sub>	TaN	Ru	Unipolar	42, 43
NdO <sub>x</sub>	TaN	Ru	Unipolar	42, 43
Ba <sub>0.7</sub> Sr <sub>0.3</sub> TiO <sub>3</sub>	SrRuO <sub>3</sub>	Pt, W	Bipolar	44
SrTiO <sub>3</sub>	SrRuO <sub>3</sub> , Au, Pt	Au, Pt	Bipolar	45
SrZrO <sub>3</sub>	SrRuO <sub>3</sub>	Au	Bipolar	46
BiFeO <sub>3</sub>	LaNiO <sub>3</sub>	Pt	Bipolar	47
Pr <sub>0.7</sub> Ca <sub>0.3</sub> MnO <sub>3</sub>	YBCO, Pt, LaAlO <sub>3</sub>	Ag	Bipolar	48
La <sub>0.33</sub> Sr <sub>0.67</sub> FeO <sub>3</sub>	Au	Al	Bipolar	49
Pr <sub>y</sub> La <sub>0.625-y</sub> Ca <sub>0.375</sub> MnO <sub>3</sub>	Ag	Ag	Bipolar	50
Nitrides (AlN)	Al, TiN, Pt	Al, TiN, Pt	Bipolar	51
Telluride (ZnTe)	Si	Au	Bipolar	52
selenide (ZnSe)	P <sup>+</sup> -Ge	In, In-Zn	Bipolar	53
Polymers	Al, ITO, Cu	Al, ITO, Cu	Bipolar	54, 55

**Table S2 | Various electrolyte materials used in cation devices (electrochemical metallization memory). Top electrode, bottom electrode, switching modes and references are also listed for each.**

Electrolytes	Bottom Electrode	Top electrode	Switching mode	reference
<b>Sulfides:</b>				
Ge <sub>x</sub> S <sub>x</sub>	W	Ag	Bipolar	56
As <sub>2</sub> S <sub>3</sub>	Au	Ag	Bipolar	57
Cu <sub>2</sub> S	Cu	Pt	Bipolar	58, 59
Zn <sub>x</sub> Cd <sub>1-x</sub> S	Pt	Ag	Bipolar	60
<b>Iodides:</b>				
AgI	Pt	Ag	Bipolar	61
RbAg <sub>4</sub> I <sub>5</sub>	Pt	Ag	Bipolar	62
<b>Selenides:</b>				
Ge <sub>x</sub> Se <sub>y</sub>	W	Ag, Cu	Bipolar	63
<b>Tellurides:</b>				
Ge <sub>x</sub> Te <sub>y</sub>	TiW	Ag	Bipolar	64
<b>Ternary chalcogenides:</b>				
Ge-Sb-Te	Mo	Au, Ag	Bipolar	65
<b>oxides</b>				
Ta <sub>2</sub> O <sub>5</sub>	Pt	Cu	Bipolar	66
SiO <sub>2</sub>	W	Cu	Uni/Bipolar	67
HfO <sub>2</sub>	Pt	Cu	Bipolar	68
WO <sub>3</sub>	Pt	Cu	Bipolar	69
ZrO <sub>2</sub>	Ag	Au	Bipolar	70
SrTiO <sub>3</sub>	Pt	Ag	Bipolar	71
TiO <sub>2</sub>	Pt	Ag	Bipolar	72
CuO <sub>x</sub>	Cu	Al	Unipolar	73
ZnO	Pt, Al doped ZnO	Cu	Bipolar	74
Al <sub>2</sub> O <sub>3</sub>	Al	Cu	Bipolar	75
MoO <sub>x</sub>	Cu	Pt	Bipolar	76
GdO <sub>x</sub>	Pt	Cu doped MoO <sub>x</sub>		77
<b>Others:</b>				
MSQ	Pt	Ag	Bipolar	78
doped organic semiconductors	Pt	Cu	Bipolar	79
nitrides	Pt	Cu	Bipolar	80
amorphous Si	P <sup>+</sup> -Si	Ag	Bipolar	81
Carbon	Pt	Cu	Bipolar	82
vacuum gaps	RbAg <sub>4</sub> I <sub>5</sub> /Ag, Ag <sub>2</sub> S/Ag	W, Pt	Bipolar	83, 84

**Table S3 | Quantitative estimates for required performance metrics.** Color indicates fidelity of the estimates, with black color standing for high fidelity, e.g. due to reported values in ITRS<sup>85</sup>, blue color for moderate fidelity, e.g. representative of some limited simulations which cannot be generalized for all cases, and red color for poorly understood requirements, obtained by general considerations but not supported with rigorous simulations.

	Storage <sup>(*)</sup>	Memory <sup>(*)</sup>	Logic	Neuro	Best reported	Comments
Reproducibility	< 10% <sup>86 (1a)</sup>	< 1% <sup>86 (1a)</sup>	< 20% <sup>87 (1b)</sup>	< 50% <sup>88, 89 (1c)</sup>	few percent <sup>(1d) 90</sup>	The numbers are for so called “stuck-on-open” defects while the requirement for other type of defects might be stricter. (1a) More efficient error correcting codes requiring large decoding latency are used in storage application. (1b) A smaller number of defects could be required for high fan-in digital logic. (1c) These applications are also quite tolerant to variations in the switching behavior <sup>91, 92</sup> . (1d) The number has still to be confirmed for crossbar circuits operation (only one memristor is turned to the ON state at a time in Ref. <sup>90</sup> while others are always kept in the OFF state).
Endurance	> 10 <sup>4</sup> (#)	> 10 <sup>16</sup> (#)	>100 <sup>(8, 2a)</sup>	>100 – 10 <sup>6</sup> <sup>(2b)</sup>	10 <sup>12</sup> <sup>[93]</sup>	(2a) The endurance requirement for material implication logic <sup>94</sup> is much higher, similar to that of memory. (2b) Larger number is for in-situ –trained networks which require modification of the weight upon learning and more demanding as compared to simple weight import with ex-situ training.
Switching energy	< 1 pJ <sup>(3a)</sup>	< 5 fJ <sup>(#)</sup>	not critical <sup>(8)</sup>	not critical <sup>(8)</sup>	1 pJ <sup>95, 96</sup>	(3a) Should be within allowable power budget (but still large enough to cause local heating)
Switching speed	< 10 μs <sup>(#)</sup>	< 1 ns <sup>(#)</sup>	not critical <sup>(8, 4a)</sup>	not critical <sup>(8, 4a, 4b)</sup>	100 ps <sup>97</sup>	(4a) Given an appropriate amount of parallelism, very slow writes might be okay. (4b) For in-situ training the speed should be fast enough to provide reasonable training time, e.g. to implement <10 <sup>6</sup> training epochs
Retention	>10 years <sup>(#)</sup>	> minutes – month <sup>(5a)</sup>	> days <sup>(8, 5b)</sup>	> seconds – days <sup>(8, 5c)</sup>	10 <sup>14</sup> <sup>[98]</sup>	(5a) Volatile memory might be still okay for many memory applications <sup>99</sup> . (5b) Infrequent refresh might be okay provided that it is much shorter than the operating time. (5c) For spiking networks a broad range of relaxation times (volatility) might be required <sup>100</sup> .
ON/OFF current ratio	> 10 <sup>(6a)</sup>	> 50 <sup>(6a)</sup>	> 100 <sup>(6a)</sup>	> 500 <sup>(6b)</sup>	> 10 <sup>11</sup> <sup>[6, 101-103]</sup>	(6a) ON/OFF current ratio affects the speed and power consumption. (6b) The requirement might be relaxed by increasing the number of states.
OFF state Resistance	> 1 MΩ	> 100 kΩ	> 10 MΩ	>100 MΩ <sup>(101)</sup>	1kΩ – 100 GΩ <sup>(101)</sup>	In general, the requirement for OFF resistance (at operating voltage) is determined by the static leakage power consumption, which is the largest in case of logic and neuromorphic applications due to their massively parallel operation. The requirement is also indirectly affected by the desired ON resistance for a given ON/OFF ratio. The ON resistance should be large enough that the voltage drop across the crossbar wire is negligible (to ensure write operation) and that the sizing (overhead) of the CMOS drivers is minimal.

I-V nonlinearity	> 100-10000 <sup>(8a)</sup>	> 100-1000 <sup>(8a)</sup>	> 10 <sup>(8b)</sup>	not critical <sup>(8c)</sup>	100 <sup>[104]</sup>	Nonlinearity is defined as $I(V_{\text{WRITE}})/I(V_{\text{WRITE}}/2)$ or $I(V_{\text{WRITE}})/I(-V_{\text{WRITE}})$ and the requirement in general scales with the number of half-selected devices (i.e. $N$ ). (8a) The requirement strongly depend on the read-out scheme and other device parameters which determine acceptable $N$ [New Ref. 1] (8b) The smallest because crossbar might be depopulated without much performance degradation. (8c) Purely linear synapses are acceptable for correct operation. Whether nonlinearity would enhance circuit performance is not well understood.
Number of states	2-16 <sup>(9a)</sup>	2 <sup>(9a)</sup>	2-16 <sup>(9b)</sup>	2-32 <sup>(9c)</sup>	~ 100 <sup>[105]</sup>	(9a) In general, the more states, the better the density is, however, at the expense of write and read latency. (9b) A larger number of states allows for more complex circuits, e.g. based on linear threshold logic <sup>[10]</sup> . (9c) The performance (e.g. for classification task) approaches its maximum value with ~5-bit weights.
density	> (10 nm) <sup>-2</sup> and > 4 layers <sup>(#)</sup>	> (10 nm) <sup>-2</sup> <sup>(#)</sup>	> (20 nm) <sup>-2</sup> & multilayer <sup>(10a, 10b)</sup>	> (10 - 100 nm) <sup>-2</sup> & multilayer <sup>(10a, 10c)</sup>	4 layer <sup>[107]</sup> 1/(10 nm) <sup>2</sup> <sup>[108]</sup>	(10a) Density is constrained by CMOS circuits. (10b) Only a small fraction of memristive devices are actively employed, i.e. turned to the ON state, for typical applications so that depopulated crossbars with relatively large devices could be acceptable without losing much routability. (10c) The higher density number would allow to exceed the density of bio-cortical circuits <sup>[109]</sup> .

Common footnotes: (#) The performance should be comparable or better than projected values by ITRS in order to compete with other emerging technologies, i.e. NAND flash and SRAM for storage and memory applications, respectively<sup>85</sup>. (&) The requirement is relaxed due to relatively infrequent changes to memristive state in these applications. (\*) Because area overhead associated with peripheral circuitry increases linearly with linear crossbar size  $N$ , while the useful area scales as  $N^2$ , naturally the larger arrays are more area efficient, however, at the expense of latency (because of larger RC delay) and possibly write/read energy<sup>86</sup>. The density (i.e. cost) should be more important for storage applications demanding larger array sizes as compared to that of fast memory applications.

1. Huang, H.-H., Shih, W.-C. & Lai, C.-H. Nonpolar resistive switching in the Pt/MgO/Pt nonvolatile memory device. *Appl. Phys. Lett.* **96**, 193505 (2010).
2. Choi, B.J. *et al.* Resistive switching mechanism of TiO<sub>2</sub> thin films grown by atomic-layer deposition. *J. Appl. Phys.* **98**, 033715 (2005).
3. Jeong, D.S., Schroeder, H. & Waser, R. Coexistence of bipolar and unipolar resistive switching behaviors in a Pt/TiO<sub>2</sub>/Pt stack. *Electrochemical and Solid State Letters* **10**, G51-G53 (2007).

4. Lee, D. *et al.* Resistance switching of the nonstoichiometric zirconium oxide for nonvolatile memory applications. *Ieee Electron Device Letters* **26**, 719-721 (2005).
5. Zhang, H. *et al.* Ionic doping effect in ZrO<sub>2</sub> resistive switching memory. *Appl. Phys. Lett.* **96**, 123502 (2010).
6. Liu, Q. *et al.* Resistive switching memory effect of ZrO<sub>2</sub> films with Zr+ implanted. *Appl. Phys. Lett.* **92**, 012117 (2008).
7. Lee, H.Y. *et al.* Low Power and High Speed Bipolar Switching with A Thin Reactive Ti Buffer Layer in Robust HfO<sub>2</sub> Based RRAM. *IEDM Tech. Dig.*, 297-300 (2008).
8. Driscoll, T. *et al.* Memory Metamaterials. *Science* **325**, 1518-1521 (2009).
9. Driscoll, T., Kim, H.T., Chae, B.G., Di Ventra, M. & Basov, D.N. Phase-transition driven memristive system. *Appl. Phys. Lett.* **95**, 3 (2009).
10. Sim, H. *et al.* Reproducible resistance switching characteristics of pulsed laser deposited polycrystalline Nb<sub>2</sub>O<sub>5</sub>. *Microelectron. Eng.* **80**, 260-263 (2005).
11. Wei, Z. *et al.* Highly Reliable TaO<sub>x</sub> ReRAM and Direct Evidence of Redox Reaction Mechanism. *IEEE International Electron Devices Meeting 2008, Technical Digest*, 293-296 (2008).
12. Yang, J.J. *et al.* High switching endurance in TaO<sub>x</sub> memristive devices. *Appl. Phys. Lett.* **97**, 232102 (2010).
13. Chen, S.-C. *et al.* Bipolar resistive switching of chromium oxide for resistive random access memory. *Solid-State Electronics* **62**, 40-43 (2011).
14. Arita, M., Kaji, H., Fujii, T. & Takahashi, Y. Resistance switching properties of molybdenum oxide films. *Thin Solid Films* **520**, 4762-4767 (2012).
15. Chien, W.C. *et al.* Unipolar Switching Behaviors of RTO WOX RRAM. *IEEE Electron Device Letters* **31**, 126-128 (2010).
16. Shang, D.S. *et al.* Improvement of reproducible resistance switching in polycrystalline tungsten oxide films by in situ oxygen annealing. *Appl. Phys. Lett.* **96**, 072103-072103 (2010).
17. Zhang, S. *et al.* Resistive switching characteristics of MnO<sub>x</sub>-based ReRAM. *Journal of Physics D-Applied Physics* **42**, 4 (2009).
18. Yang, M.K., Park, J.-W., Ko, T.K. & Lee, J.-k. Resistive switching characteristics of TiN/MnO<sub>2</sub>/Pt memory devices. *physica status solidi (RRL) – Rapid Research Letters* **4**, 233-235 (2010).
19. Odagawa, A. *et al.* Electroforming and resistance-switching mechanism in a magnetite thin film. *Appl. Phys. Lett.* **91**, 133503 (2007).
20. Inoue, I.H., Yasuda, S., Akinaga, H. & Takagi, H. Nonpolar resistance switching of metal/binary-transition-metal oxides/metal sandwiches: Homogeneous/inhomogeneous transition of current distribution. *Physical Review B* **77**, 035105 (2008).
21. Shima, H. *et al.* Resistance switching in the metal deficient-type oxides: NiO and CoO. *Appl. Phys. Lett.* **91** (2007).
22. Seo, S. *et al.* Reproducible resistance switching in polycrystalline NiO films. *Appl. Phys. Lett.* **85**, 5655-5657 (2004).
23. Park, C. *et al.* Role of structural defects in the unipolar resistive switching characteristics of Pt/NiO/Pt structures. *Appl. Phys. Lett.* **93**, 042102 (2008).
24. Yang, W.-Y. & Rhee, S.-W. Effect of electrode material on the resistance switching of Cu<sub>2</sub>O film. *Appl. Phys. Lett.* **91**, 232907-232903 (2007).
25. Xu, N. *et al.* Characteristics and mechanism of conduction/set process in TiN/ZnO/Pt resistance switching random-access memories. *Appl. Phys. Lett.* **92** (2008).
26. Qi, J. *et al.* Resistive Switching in Single Epitaxial ZnO Nanoislands. *Acs Nano* **6**, 1051-1058 (2012).
27. Song, J., Zhang, Y., Xu, C., Wu, W. & Wang, Z.L. Polar Charges Induced Electric Hysteresis of ZnO Nano/Microwire for Fast Data Storage. *Nano Lett.* **11**, 2829-2834 (2011).

28. Kim, K.M. *et al.* Resistive switching in Pt/Al<sub>2</sub>O<sub>3</sub>/TiO<sub>2</sub>/Ru stacked structures. *Electrochemical and Solid State Letters* **9**, G343-G346 (2006).
29. Lin, C.Y., Wu, C.Y., Hu, C. & Tsenga, T.Y. Bistable resistive switching in Al<sub>2</sub>O<sub>3</sub> memory thin films. *J. Electrochem. Soc.* **154**, G189-G192 (2007).
30. Gao, X. *et al.* Effect of top electrode materials on bipolar resistive switching behavior of gallium oxide films. *Appl. Phys. Lett.* **97**, 193501-193503 (2010).
31. Yao, J., Zhong, L., Natelson, D. & Tour, J. Intrinsic resistive switching and memory effects in silicon oxide. *Appl. Phys. A* **102**, 835-839 (2011).
32. Huang, R. *et al.* Resistive switching of silicon-rich-oxide featuring high compatibility with CMOS technology for 3D stackable and embedded applications. *Applied Physics A: Materials Science & Processing* **102**, 927-931 (2011).
33. Hsu, C.-H. *et al.* Optical, electrical properties and reproducible resistance switching of GeO<sub>2</sub> thin films by sol-gel process. *Thin Solid Films* **519**, 5033-5037 (2011).
34. Cheng, C.H. *et al.* Bipolar switching characteristics of low-power Geo resistive memory. *Solid-State Electronics* **62**, 90-93.
35. Nagashima, K., Yanagida, T., Oka, K. & Kawai, T. Unipolar resistive switching characteristics of room temperature grown SnO<sub>2</sub> thin films. *Appl. Phys. Lett.* **94**, 242902-242902-242903 (2009).
36. Tulina, N.A., Borisenko, I.Y., Ionov, A.M. & Shmyt'ko, I.M. Bipolar resistive switching in heterostructures: Bismuth oxide/normal metal. *Solid State Commun.* **150**, 2089-2092 (2010).
37. Youngbae, A. *et al.* Concurrent presence of unipolar and bipolar resistive switching phenomena in pnictogen oxide Sb<sub>[sub 2]</sub>O<sub>[sub 5]</sub> films. *J. Appl. Phys.* **112**, 114105 (2012).
38. Huang, S.Y. *et al.* Resistive switching characteristics of Sm<sub>2</sub>O<sub>3</sub> thin films for nonvolatile memory applications. *Solid-State Electronics* **63**, 189-191 (2011).
39. Cao, X. *et al.* Forming-free colossal resistive switching effect in rare-earth-oxide Gd<sub>2</sub>O<sub>3</sub> films for memristor applications. *J. Appl. Phys.* **106**, 073723-073723-073725 (2009).
40. Pi, C., Ren, Y., Liu, Z.Q. & Chim, W.K. Unipolar Memristive Switching in Yttrium Oxide and RESET Current Reduction Using a Yttrium Interlayer. *Electrochem. Solid-State Lett.* **15**, G5-G7 (2012).
41. Sun, X. *et al.* Resistive Switching in CeO<sub>x</sub> Films for Nonvolatile Memory Application. *Ieee Electron Device Letters* **30**, 334-336 (2009).
42. Pan, T.-M. & Lu, C.-H. Forming-free resistive switching behavior in Nd<sub>[sub 2]</sub>O<sub>[sub 3]</sub>, Dy<sub>[sub 2]</sub>O<sub>[sub 3]</sub>, and Er<sub>[sub 2]</sub>O<sub>[sub 3]</sub> films fabricated in full room temperature. *Appl. Phys. Lett.* **99**, 113509-113503 (2011).
43. Pan, T.M. & Lu, C.H. Switching Behavior in Rare-Earth Films Fabricated in Full Room Temperature. *Ieee Transactions on Electron Devices* **59**, 956-961 (2012).
44. Shen, W., Dittmann, R., Breuer, U. & Waser, R. Improved endurance behavior of resistive switching in (Ba,Sr)TiO<sub>3</sub> thin films with W top electrode. *Appl. Phys. Lett.* **93**, 222102 (2008).
45. Szot, K., Speier, W., Bihlmayer, G. & Waser, R. Switching the electrical resistance of individual dislocations in single-crystalline SrTiO<sub>3</sub>. *Nature Materials* **5**, 312-320 (2006).
46. Beck, A., Bednorz, J.G., Gerber, C., Rossel, C. & Widmer, D. Reproducible switching effect in thin oxide films for memory applications. *Appl. Phys. Lett.* **77**, 139-141 (2000).
47. Chen, X.M., Zhang, H., Ruan, K.B. & Shi, W.Z. Annealing effect on the bipolar resistive switching behaviors of BiFeO<sub>3</sub> thin films on LaNiO<sub>3</sub>-buffered Si substrates. *J. Alloys Compd.* **529**, 108-112 (2012).
48. Liu, S.Q., Wu, N.J. & Ignatiev, A. Electric-pulse-induced reversible resistance change effect in magnetoresistive films. *Appl. Phys. Lett.* **76**, 2749-2751 (2000).
49. Hamaguchi, M., Aoyama, K., Asanuma, S., Uesu, Y. & Katsufuji, T. Electric-field-induced resistance switching universally observed in transition-metal-oxide thin films. *Appl. Phys. Lett.* **88** (2006).

50. Quintero, M., Levy, P., Leyva, A.G. & Rozenberg, M.J. Mechanism of electric-pulse-induced resistance switching in manganites. *Phys. Rev. Lett.* **98** (2007).
51. Choi, B.J. *et al.* Nitride memristors. *Applied Physics A: Materials Science & Processing* **109**, 1-4 (2012).
52. Patel, N.G. Some observations on the switching and memory phenomena in ZnTe-Si. *Journal of Materials Science* **21**, 2097-2099 (1986).
53. Hovel, H.J. Switching and memory in ZnSe/Ge heterojunctions. *Appl. Phys. Lett.* **17**, 141-143 (1970).
54. Yang, Y., Ouyang, J., Ma, L., Tseng, R.J.H. & Chu, C.W. Electrical switching and bistability in organic/polymeric thin films and memory devices. *Adv. Funct. Mater.* **16**, 1001-1014 (2006).
55. Lee, T. & Chen, Y. Organic resistive nonvolatile memory materials. *MRS Bull.* **37**, 144-149 (2012).
56. Russo, U., Kamalanathan, D., Ielmini, D., Lacaita, A.L. & Kozicki, M.N. Study of Multilevel Programming in Programmable Metallization Cell (PMC) Memory. *Electron Devices, IEEE Transactions on* **56**, 1040-1047 (2009).
57. Stratani, I., Tsilulyanu, D. & Eisele, I. A programmable metallization cell based on Ag-As2S3. *Journal of Optoelectronics and Advanced Materials* **8**, 2117-2119 (2006).
58. Banno, N., Sakamoto, T., Hasegawa, T., Terabe, K. & Aono, M. Effect of ion diffusion on switching voltage of solid-electrolyte nanometer switch. *Japanese Journal of Applied Physics Part 1-Regular Papers Brief Communications & Review Papers* **45**, 3666-3668 (2006).
59. Nayak, A. *et al.* Controlling the Synaptic Plasticity of a Cu2S Gap-Type Atomic Switch. *Adv. Funct. Mater.* **22**, 3606-3613 (2012).
60. Wang, Z. *et al.* Resistive switching mechanism in ZnxCd1-xS nonvolatile memory devices. *Electron Device Letters, IEEE* **28**, 14-16 (2007).
61. Liang, X.F. *et al.* Resistive switching and memory effects of AgI thin film. *J. Phys. D: Appl. Phys.* **40**, 4767 (2007).
62. Liang, X.F., Chen, Y., Chen, L., Yin, J. & Liu, Z.G. Electric switching and memory devices made from RbAg4I5 films. *Appl. Phys. Lett.* **90**, 022508-022503 (2007).
63. Mitkova, M. & Kozicki, M.N. Mass transport in chalcogenide electrolyte films - materials and applications. *J. Non-Cryst. Solids* **352**, 567-577 (2006).
64. Kim, C.J. *et al.* Characterization of silver-saturated Ge-Te chalcogenide thin films for nonvolatile random access memory. *Journal of Vacuum Science & Technology B* **24**, 721-724 (2006).
65. Pandian, R., Kooi, B.J., Palasantzas, G., De Hosson, J.T.M. & Pauza, A. Polarity-dependent reversible resistance switching in Ge-Sb-Te phase-change thin films. *Appl. Phys. Lett.* **91**, 152103 (2007).
66. Sakamoto, T. *et al.* Electronic transport in Ta2O5 resistive switch. *Appl. Phys. Lett.* **91**, 092110 (2007).
67. Schindler, C., Thermadam, S.C.P., Waser, R. & Kozicki, M.N. Bipolar and unipolar resistive switching in Cu-doped SiO<sub>2</sub>. *ieee Transactions on Electron Devices* **54**, 2762-2768 (2007).
68. Haemori, M., Nagata, T. & Chikyow, T. Impact of Cu Electrode on Switching Behavior in a Cu/HfO<sub>2</sub>/Pt Structure and Resultant Cu Ion Diffusion. *Applied Physics Express* **2**, 3 (2009).
69. Li, Y. *et al.* Nonvolatile multilevel memory effect in Cu/WO<sub>3</sub>/Pt device structures. *physica status solidi (RRL) – Rapid Research Letters* **4**, 124-126 (2012).
70. Li, Y.T. *et al.* Resistive Switching Properties of Au/ZrO<sub>2</sub>/Ag Structure for Low-Voltage Nonvolatile Memory Applications. *ieee Electron Device Letters* **31**, 117-119 (2010).
71. Yan, X.B. *et al.* The Resistive Switching Mechanism of Ag/SrTiO<sub>3</sub>/Pt Memory Cells. *Electrochemical and Solid State Letters* **13**, H87-H89 (2010).
72. Tsunoda, K. *et al.* Bipolar resistive switching in polycrystalline TiO<sub>2</sub> films. *Appl. Phys. Lett.* **90**, 113501-113503 (2007).

73. Lv, H.B. *et al.* Forming process investigation of Cu<sub>x</sub>O memory films. *Ieee Electron Device Letters* **29**, 47-49 (2008).
74. Peng, S. *et al.* Mechanism for resistive switching in an oxide-based electrochemical metallization memory. *Appl. Phys. Lett.* **100**, 072101-072104 (2012).
75. Kever, T., Bottger, U., Schindler, C. & Waser, R. On the origin of bistable resistive switching in metal organic charge transfer complex memory cells. *Appl. Phys. Lett.* **91**, 083506 (2007).
76. Lee, D. *et al.* Resistance switching of copper doped MoO<sub>[sub x]</sub> films for nonvolatile memory applications. *Appl. Phys. Lett.* **90**, 122104-122103 (2007).
77. Yoon, J. *et al.* Excellent Switching Uniformity of Cu-Doped MoO<sub>x</sub>/GdO<sub>x</sub> Bilayer for Nonvolatile Memory Applications. *Ieee Electron Device Letters* **30**, 457-459 (2009).
78. Meier, M. *et al.* A Nonvolatile Memory With Resistively Switching Methyl-Silsesquioxane. *Ieee Electron Device Letters* **30**, 8-10 (2009).
79. Chen, L. *et al.* Nonvolatile memory devices with Cu<sub>2</sub>S and Cu-Pc bilayered films. *Appl. Phys. Lett.* **91**, 073511-073513 (2007).
80. Chen, C., Yang, Y.C., Zeng, F. & Pan, F. Bipolar resistive switching in Cu/AlN/Pt nonvolatile memory device. *Appl. Phys. Lett.* **97**, 083502-083503 (2010).
81. Jo, S.H., Kim, K.H. & Lu, W. Programmable Resistance Switching in Nanoscale Two-Terminal Devices. *Nano Lett.* **9**, 496-500 (2009).
82. Zhuge, F. *et al.* Nonvolatile resistive switching memory based on amorphous carbon. *Appl. Phys. Lett.* **96**, 163505-163503 (2010).
83. Valov, I. *et al.* Atomically controlled electrochemical nucleation at superionic solid electrolyte surfaces. *Nature Mater.* **11**, 530-535 (2012).
84. Terabe, K., Hasegawa, T., Nakayama, T. & Aono, M. Quantized conductance atomic switch. *Nature* **433**, 47-50 (2005).
85. ITRS International Technology Roadmap for Semiconductors, 2011 Edition, available online at <http://www.itrs.net>. (2011).
86. Strukov, D.B. & Likharev, K.K. Defect-tolerant architectures for nanoelectronic crossbar memories. *Journal of Nanoscience and Nanotechnology* **7**, 151-167 (2007).
87. Strukov, D.B. & Likharev, K.K. CMOL FPGA: a reconfigurable architecture for hybrid digital circuits with two-terminal nanodevices. *Nanotechnology* **16**, 888 (2005).
88. Turel, O., Lee, J.H., Ma, X.L. & Likharev, K.K. Neuromorphic architectures for nanoelectronic circuits. *International Journal of Circuit Theory and Applications* **32**, 277-302 (2004).
89. Lee, J.H. & Likharev, K.K. Defect-tolerant nanoelectronic pattern classifiers. *International Journal of Circuit Theory and Applications* **35**, 239-264 (2007).
90. Kim, K.-H. *et al.* A Functional Hybrid Memristor Crossbar-Array/CMOS System for Data Storage and Neuromorphic Applications. *Nano Lett.* **12**, 389-395 (2012).
91. Snider, G.S. Self-organized computation with unreliable, memristive nanodevices. *Nanotechnology* **18**, 365202 (2007).
92. Querlioz, D., Bichler, O. & Gamrat, C. in Neural Networks (IJCNN), The 2011 International Joint Conference on 1775-17812011).
93. Lee, M.-J. *et al.* A fast, high-endurance and scalable non-volatile memory device made from asymmetric Ta<sub>2</sub>O<sub>5-x</sub>/Ta<sub>2</sub>O<sub>2-x</sub> bilayer structures. *Nature Mater.* **10**, 625-630 (2011).
94. Borghetti, J. *et al.* 'Memristive' switches enable 'stateful' logic operations via material implication. *Nature* **464**, 873-876 (2010).
95. Miao, F. *et al.* Anatomy of a Nanoscale Conduction Channel Reveals the Mechanism of a High-Performance Memristor. *Adv. Mater.* **23**, 5633-5640 (2011).

96. Strachan, J.P., Torrezan, A.C., Medeiros-Ribeiro, G. & Williams, R.S. Measuring the switching dynamics and energy efficiency of tantalum oxide memristors. *Nanotechnology* **22**, 505402 (2011).
97. Torrezan, A.C., Strachan, J.P., Medeiros-Ribeiro, G. & Williams, R.S. Sub-nanosecond switching of a tantalum oxide memristor. *Nanotechnology* **22**, 485203 (2011).
98. Chen, A. *et al.* Non-volatile resistive switching for advanced memory applications, in *Ieee International Electron Devices Meeting 2005, Technical Digest* 765-768 (Ieee, New York; 2005).
99. Smullen, C.I., Mohan, V., Nigam, A., Gurumurthi, S. & Stan, M.R. Relaxing Non-Volatility for Fast and Energy-Efficient STT-RAM Caches, in *2011 IEEE 17th International Symposium on High-Performance Computer Architecture* 50-61 (IEEE Computer Soc, Los Alamitos; 2011).
100. Ohno, T. *et al.* Short-term plasticity and long-term potentiation mimicked in single inorganic synapses. *Nat Mater* **10**, 591-595 (2011).
101. Schindler, C., Vol. Ph. D2009.
102. Banno, N. *et al.* Diffusivity of Cu Ions in Solid Electrolyte and Its Effect on the Performance of Nanometer-Scale Switch. *Electron Devices, IEEE Transactions on* **55**, 3283-3287 (2008).
103. Hahm, S.G. *et al.* Novel Rewritable, Non-volatile Memory Devices Based on Thermally and Dimensionally Stable Polyimide Thin Films. *Adv. Funct. Mater.* **18**, 3276-3282 (2008).
104. Yang, J.J. *et al.* Engineering nonlinearity into memristors for passive crossbar applications. *Appl. Phys. Lett.* **100**, 113501 (2012).
105. Alibart, F., Gao, L.G., Hoskins, B.D. & Strukov, D.B. High precision tuning of state for memristive devices by adaptable variation-tolerant algorithm. *Nanotechnology* **23**, 075201 (2012).
106. Gao, L., Alibart, F. & Strukov, D.B. Configurable CMOS/memristor threshold gate. Available online at <http://www.ece.ucsb.edu/~strukov/threshold.pdf> under review (2012).
107. Kawahara, A. *et al.* An 8Mb multi-layered cross-point ReRAM macro with 443MB/s write throughput. *Solid-State Circuits Conference Digest of Technical Papers (ISSCC), 2012 IEEE International*, 432-434 (2012).
108. Govoreanu, B. *et al.* 10×10 nm<sup>2</sup> Hf/HfO<sub>x</sub> crossbar resistive RAM with excellent performance, reliability and low-energy operation. *Electron Devices Meeting (IEDM), 2011 IEEE International*, 31.36.31-31.36.34.
109. Likharev, K., Mayr, A., Muckra, I. & TÜRel, Ö. CrossNets: High-Performance Neuromorphic Architectures for CMOL Circuits. *Ann. N.Y. Acad. Sci.* **1006**, 146-163 (2003).